



HE UNITED STATES PATENT AND TRADEMARK OFFICE

Application No.:

10/712,775

Group Art Unit:

1765

Filing Date:

November 14, 2003

Examiner:

Anita K. Alanko

Applicant:

Donggyun Han et al.

Title:

METHOD FOR REMOVING

AND PHOTORESIST FROM A SUBSTRATE

Attorney Docket:

2557-000216/US

APPARATUS

Customer Service Window

December 29, 2005

Randolph Building 401 Dulany Street Alexandria, VA 22314 Mail Stop Amendment

AMENDMENT

Sir:

In response to the Office Action mailed September 29, 2005, the following amendments and remarks are respectfully submitted in connection with the above-identified application.

Amendments to the Claims begin on page 2 of this Amendment.

Remarks begin on page 8 of this Amendment.

	Claims remaining after Amendment		Highest number previously paid for		Present extra
Total	40	-	50	=	0
Independent	3	-	4	=	0